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In addition to larger original papers brief reports will be published of the authors, own research work. The report should be set out according to the above guide lines.

The Editorial Board invites the readers to send over any remarks or observations referring to the publications which will appear in the Optica Applicata. The correspondence of essential importance will be published in a separate column dealing with Letters to the Editor.

Review of matter

Application of the diffraction theory. quantum optics, problems in radiation coherence, light sources, holography and its application, scientific photography, methods of image reconstruction, optical application of Fourier transforms, theory of optical systems, criteria of optical image evaluation, optical materials, technology of manufacturing optical elements, aspheric optics, optical properties of solids and thin films, lasers and their application, photo- and radiometry, problems in spectroscopy, non-linear optics, optical data processing, optical measurements, fibre optics optical instrumentation, interferometry, microscopy, nonvisible optics, automation of optical computing, optoelectronics, colorimetry, optical detectors, elipsometry and photoelasticity.

OPTICA VIII APPLICATA 1

Contents

F. KACZMAREK, A. JENDRZEJCZAK, Second harmonic

generation (SHG) and frequency mixing (FM) in in-	
frared He-Ne laser beams in KDP crystal	3
F. Firszt, H. L. Oczkowski, Efficiency measurements	
on electroluminescent devices	9
Z. CHORVATOVA, R. HAJOSSY, On measurement of neutral	
gas temperature in the plasma of a spark plug	15
P. BECLA, J. F. KASPRZAK, J. M. PAWLIKOWSKI, PEM-effect	
in graded up $Cd_xHg_{1-x}Te$ layers	21
M. GAJ, The influence of the layer thickness on the	
coupling efficiency of plane waveguide with periodical-	
ly variable refractive index	29
S. Kusch, R. Guther, Classification of structures by thick	
holograms	35
J. KEPRT, M. HRABOVSKÝ, P. VEJBOR, Usage of materials	
with low resolving power in holographic interferometry	37
E. Dobierzewska-Mozrzymas, Surface-roughness influ-	
ence on the optical properties of aluminium films.	43
Содержание	
A Townson A Company Covers Proper	
- О - КАЧМАРЕК - А. Е.Н.ІЖЕЙЧАК, ГЕНЕОИООВИНИЕ ВТОООИ	
Ф. Качмарек, А. Енджейчак, Генерирование второй гармоники и оптическое смешение инфракрасных	
гармоники и оптическое смешение инфракрасных	3
гармоники и оптическое смешение инфракрасных пучиов лазера He-Ne,	3
гармоники и оптическое смешение инфракрасных пучиов лазера He-Ne,	_
гармоники и оптическое смешение инфракрасных пучиов лазера He-Ne,	3
гармоники и оптическое смешение инфракрасных пучиов лазера He-Ne,	9
гармоники и оптическое смешение инфракрасных пучиов лазера Не-Ne,	_
гармоники и оптическое смешение инфракрасных пучиов лазера Не-Ne,	9
гармоники и оптическое смешение инфракрасных пучиов лазера He-Ne,	9
гармоники и оптическое смешение инфракрасных пучиов лазера He-Ne,	9
гармоники и оптическое смешение инфракрасных пучиов лазера He-Ne,	9
гармоники и оптическое смешение инфракрасных пучиов лазера He-Ne,	9 15 21
гармоники и оптическое смешение инфракрасных пучиов лазера He-Ne,	9
гармоники и оптическое смешение инфракрасных пучиов лазера He-Ne,	9 15 21 29
гармоники и оптическое смешение инфракрасных пучиов лазера He-Ne,	9 15 21
гармоники и оптическое смешение инфракрасных пучиов лазера He-Ne,	9 15 21 29
гармоники и оптическое смешение инфракрасных пучиов лазера He-Ne,	9 15 21 29 35
гармоники и оптическое смешение инфракрасных пучиов лазера He-Ne,	9 15 21 29
гармоники и оптическое смешение инфракрасных пучиов лазера He-Ne,	9 15 21 29 35

Short Anounsments

The fourth Polish-Czechoslovak Optical Conference

will be held on September 19-22, 1978 in Rynia near Zalew Zegrzyński (25 km from Warsaw).

The Conference purpose is:

- 1. A review of newest achievements in the field of design and technology of optical instruments.
- 2. An exchange of opinions on the state of theoretical and experimental research in applied optics.
- 3. Widening of personal contacts and deepening the cooperation between scientific and industrial institutions of both the countries.

The debate will be held in two sections:

- section A: physical and laser optics,
- section B: instrumental optics and new technologies.

The conference will be accompanied by an exhibition of optical instruments and devices produced or prepared for production by Polish Optical Works and scientific institutions of Warsaw.

The conference organizers are:

- 1. Institute of Design of Precise and Optical Instruments Technical University of Warsaw,
 - 2. Industrial Union "Omel",
 - 3. Central Optical Laboratory,
- 4. Optical section of SIMP with colaboration of Professional Training Section of SIMP,
 - 5. Polish Optical Works.

The 11th Meeting of the International Commission for Optics and the Associated International Conference "Optica hoy y Mañana"

will be held at the Consejo Superior de Investigaciones Cientificas (National Research Council) in Madrid, Spain, from 10 to 17 September 1978.

The Conference is sponsored by the International Commission for Optics and organized by the Spanish National Committee, with the colaboration of Instituto de Optica "Daza de Valdes" and Sociedad Española de Optica.

General items of the meeting

Election of the Bureau,

Examination of the Financial Statement presented by the Bureau.

Agreement on a provisional budget for future years, Discussion of questions submitted by the different National Committees, the Bureau or the Executive Committee of IUPAP.

General fields of the Conference

Vision.

Image Formation and Processing, Optical Physics.